

Marked-Up Copy
Serial No: 09/147,520
Amendment Filed on: 6/4/02

IN THE CLAIMS:

Please cancel claims 1, 4, 9, and 10, without prejudice or disclaimer, and amend claims 5, 11, and 12, as follows:

1. (Canceled).

4. (Canceled).

5. (Thrice Amended) A surface inspection method comprising the steps of:

irradiating a surface of an object to be measured with an irradiation light , said irradiation light being reflected from a light source onto the surface of the object to be measured to form a reflected light;

making a component of said reflected light, parallel with an optical axis of an objective lens provided oppositely to the object to be measured, incident on a slit through said objective lens to form an incident light;

switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and a dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens

such that there is a focus on the surface of the object to be measured, wherein an angle at which a difference from the normal position is obviously observed with the naked eye is selected, and bright-field illumination is used when the angle is zero degrees and dark-field illumination is used when the angle is an angle other than zero degrees;

receiving only a component of said incident light having passed through an opening of said slit to form a received light;

obtaining a light quantity of said received light; and

controlling a light detection extent in the surface of the object to be measured by changing a size of said opening of said slit to be within a range of between approximately 0.2 mm to approximately 30 mm and by changing a magnification of said objective lens.

9. (Canceled).

10. (Canceled).

11. (Thrice Amended) A surface inspection method comprising the steps of:

irradiating a surface of an object to be measured with a light to form an irradiation light;

reflecting said irradiation light on the surface of the object to be measured to form a reflected light;

making only a component in almost one direction incident on a slit through a tubular member in the reflected light to form an incident light;

switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said

objective lens, and a dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured, wherein an angle at which a difference from the normal position is obviously observed with the naked eye is selected, and bright-field illumination is used when the angle is zero degrees and dark-field illumination is used when the angle is an angle other than zero degrees;

obtaining only a component of a light quantity through an opening of said slit in said incident light; and

controlling a light detection extent in the surface of the object to be measured by changing a size of said opening of said slit to be within a range of approximately 0.2 mm to approximately 30 mm and by changing a magnification of said objective lens.

12. (Thrice Amended) A surface inspection method comprising the steps of:
irradiating a surface of an object to be measured with a light to form an irradiation light;

reflecting said irradiation light on the surface of the object to be measured to form a reflected light;

making said reflected light incident on a slit through an optical fiber cable to form an incident light;

switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and a dark-field illumination, in which said light from said light source is

made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured, wherein an angle at which a difference from the normal position is obviously observed with the naked eye is selected, and bright-field illumination is used when the angle is zero degrees and dark-field illumination is used when the angle is an angle other than zero degrees;

obtaining a light quantity of only a component having passed through an opening of said slit in said incident light; and

controlling a light detection extent in the surface of the object to be measured by changing a size of said opening of said slit to be within a range of approximately 0.2 mm to approximately 30 mm and by changing a magnification of said objective lens.